

## PATENT APPLICATION

**Technology Center 2100** 

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE In re Application of: Examiner: P. L. Rodriguez Keiji EMOTO Group Art Unit: 2125 Application No.: 09/833,766 Confirmation No.: 4154 Filed: April 13, 2001 For: PIPE STRUCTURE, ALIGNMENT APPARATUS, June 2, 2004 **ELECTRON BEAM LITHOGRAPHY** APPARATUS, EXPOSURE APPARATUS, EXPOSURE APPARATUS MAINTENANCE **RECEIVED** METHOD, SEMICONDUCTOR DEVICE MANUFACTURING METHOD, AND SEMI-JUN 0 7 2004 CONDUCTOR MANUFACTURING FACTORY

**Mail Stop RCE** 

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## **PRELIMINARY AMENDMENT**

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: